

Scepter X2™ Automated Connector Polishing System

DUAL POSITION OPTICAL POLISHING

DOUBLES CAPACITY OF STANDARD SCEPTER™

EXTERNAL PC CONTROL WITH MICROFEED™

INDEPENDENT SUSPENSION WORKHOLDERS

SUPPORTS ALL INDUSTRY STANDARD CONNECTORS / MIL-TERMINI / FERRULES

AIR POLISHING IN MACHINE

TELCORDIA COMPLIANT

SPECIFICATIONS AND FEATURES

Polishing Performance¹

Apex Offset

<50 microns, maximum <15 microns, typical Radius of Curvature

10-25 mm, 2.5 mm ferrules 7-20 mm, 1.25 mm ferrules 5-12 mm, APC ferrules

Undercut/Protrusion² 0 to -100 nm

¹ Polishing performance meets and exceeds Telecordia specifications, and can be optimized for specific applications. ² Dependent upon radius of curvature.

Optical Performance³

Back Reflection < -60 dB, UPC < -65 dB, APC

Insertion Loss < 0.25 dB, typical

³Optical performance may vary between connector manufacturers.

Program Description FCAPC program . Name/Instructions Polishing MicroFeed Pad Color Polish Polish Polish	Simu Universal Workholder Referencing Routine MicroFeed Polish Routine Cycle Time (1-999 sec) Pressure (inches travel) 0R Micro Steps (1 - 300,000) Platen Speed (fevs/sec) FCAPCDENUB Image: Control of the stravel Sector of the stravel Image: Control of the stravel Sector of the stravel Sector of the stravel Image: Control of the stravel Sector of the stravel
Step Process Name Instructions Pad Color Polish If 1 Denub 3 num SiC on Drange Drang I If Step 1 I If 2 [5 um Diamond 6 um Diamond on Drange w/water Drang I If Step 2 I	Routine (1'9999 sec) (inches travel) UH (1 - 300,000) (rever/sec) FCAPCDENUB 0 6 • 0 III •
	Image: 30 c 1.3 c 20000 11.5 Image: 1.5
BOIT HicroFeed Polish Routine Routine Name FCAPCDENUB Description FCAPCDENUB Stat Position 234732 Image: Comparison of the state of the sta	Image: Constraint of the second state of the second sta

Scepter features an intuitive user interface for creating polishing programs. All polishing parameters including cycle time, pressure and speed settings are easily inputted for all connector types and desired surface geometries.

Specifications subject to change without notice Rev. 1, 4/17



Operational

Connector Capacity 24 connectors using Independent Suspension workholders 58 connectors with high capacity workholders Connector Support All industry standard, MIL-spec and custom connectors/termini Process Time⁴

Approximately 3 to 8 sec/connector **Polishing Pressure**

Programmable, sub-micron, automated, linear displacement

Polishing Speed Program selectable Cycling Timing Program selectable

Polishing Motion Random orbital

⁴ Singlemode UPC finish.



Scepter workholders feature Independent Suspension (IS) at each connector position for controlled pressure and uniform contact with the polishing surface. IS permits air polishing while maximizing film life. Each position is optically aligned for optimal polish geometry using KrellTech's patented technology.